

Qiu Xu

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/9931380/publications.pdf>

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papers

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1307594

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citing authors

| # | ARTICLE | IF | CITATIONS |
|---|---|-----|-----------|
| 1 | Multi-Threshold Inertial Switch With Acceleration Direction Detection Capability. IEEE Transactions on Industrial Electronics, 2023, 70, 4226-4235. | 7.9 | 7 |
| 2 | Design, modeling, and testing of a bidirectional multi-threshold MEMS inertial switch. Sensors and Actuators A: Physical, 2022, 334, 113219. | 4.1 | 9 |
| 3 | Micromachined threshold inertial switches: a review. Journal of Micromechanics and Microengineering, 2022, 32, 063001. | 2.6 | 7 |
| 4 | Multi-Threshold Inertial Switch for Quantitative Acceleration Measurements. IEEE Sensors Journal, 2021, 21, 23849-23859. | 4.7 | 14 |
| 5 | Multi-Threshold MEMS Shock Sensor for Quantitative Acceleration Measurements. , 2021, , . | | 0 |
| 6 | Design and characterization of an inertial microswitch with synchronous follow-up flexible compliant electrodes capable of extending contact duration. Sensors and Actuators A: Physical, 2018, 270, 34-45. | 4.1 | 12 |
| 7 | Shock-Resistibility of MEMS-Based Inertial Microswitch under Reverse Directional Ultra-High g Acceleration for IoT Applications. Scientific Reports, 2017, 7, 45512. | 3.3 | 22 |
| 8 | Design and Optimization of a Stationary Electrode in a Vertically-Driven MEMS Inertial Switch for Extending Contact Duration. Sensors, 2017, 17, 527. | 3.8 | 9 |
| 9 | A surface-micromachining-based inertial micro-switch with compliant cantilever beam as movable electrode for enduring high shock and prolonging contact time. Applied Surface Science, 2016, 387, 569-580. | 6.1 | 22 |